City University of Hong Kong Course Syllabus

offered by Department of Physics with effect from Semester A 2022/23

Part I Course Overview

Course Title:	Modern Characterization Techniques for Materials Physics
Course Code:	РНУ8501
Course Duration:	One Semester
Credit Units:	3
Level:	R8
Medium of Instruction:	English
Medium of Assessment:	English
Prerequisites : (Course Code and Title)	Nil
Precursors : <i>(Course Code and Title)</i>	Nil
Equivalent Courses : (Course Code and Title)	AP8301 Instrumental Methods of Analysis and Laboratory
Exclusive Courses : (Course Code and Title)	PHY5501 Modern Characterization Techniques for Materials Physics

Part II Course Details

1. Abstract

This is a survey course for discussing both the physical principles and practical applications of modern methods for materials characterization. The course is designed for graduate students in applied physics and engineering disciplines related to materials research. The goal is to provide students with a foundation in the use of characterization techniques to solve and diagnose material problems that can be identified and potentially resolved with materials characterization.

The course covers techniques of microstructural analysis (OM, SEM, TEM, electron diffraction, XRD), microchemical characterization (EDS, XPS, AES, SIMS, RBS, and Raman spectroscopy), various scanning probe microscopy techniques (AFM, STM, EFM, and MFM) as well as electrical (Hall, CV, Seebeck) and optical measurements (UV-Vis-NIR, Ellipsometry, PL, etc). It emphasizes on the information that can be obtained together with the advantages and limitations of each technique. The course has a laboratory component with written lab reports and a term paper.

2. Course Intended Learning Outcomes (CILOs)

No.	CILOs	Weighting* (if applicable)	Discov curricu learnin (please approp	very-enn ilum rel ig outco e tick priate)	riched lated omes where
			AI	A2	A3
1.	Describe the physical principles of various analytical instruments.			\checkmark	
2.	Apply physical principles to the structural design of each element of the instruments, in particular to those involving electron beam and ion beam.			\checkmark	
3.	Apply selected analytical techniques to common applications.		\checkmark		\checkmark
4.	Develop an in-depth knowledge in selected techniques and how they can be applied to specific problems in research in materials physics		\checkmark	\checkmark	\checkmark
		100%			

A1: Attitude

Develop an attitude of discovery/innovation/creativity, as demonstrated by students possessing a strong sense of curiosity, asking questions actively, challenging assumptions or engaging in inquiry together with teachers.

- A2: Ability Develop the ability/skill needed to discover/innovate/create, as demonstrated by students possessing critical thinking skills to assess ideas, acquiring research skills, synthesizing knowledge across disciplines or applying academic knowledge to self-life problems.
- A3: Accomplishments Demonstrate accomplishment of discovery/innovation/creativity through producing /constructing creative works/new artefacts, effective solutions to real-life problems or new processes.

3. Teaching and Learning Activities (TLAs)

TLA	Brief Description	CILO No.			Hours/week (if		
		1	2	3	4		applicable)
Lectures	Introduce various techniques, explain the relevant concepts and applications	V	V	V			3

Term paper	Apply the knowledge to solve practical problems.	\checkmark	\checkmark	\checkmark	\checkmark		
Laboratories	Conduct relevant experiments to obtain practical understanding on selected techniques	V	\checkmark	\checkmark	\checkmark		

4. Assessment Tasks/Activities (ATs)

Assessment Tasks/Activities	CILO No.					Weighting*	Remarks
	1	2	3	4			
Continuous Assessment: 50%							
Laboratories	\checkmark	\checkmark	\checkmark	\checkmark		30%	
Term paper	\checkmark	\checkmark	\checkmark	\checkmark		20%	
Examination: (duration: 2 hrs)	\checkmark	\checkmark	\checkmark	\checkmark		50%	
						100%	

5. Assessment Rubrics

Applicable to students admitted in Semester A 2022/23 and thereafter

Assessment Task	Criterion	Excellent	Good	Marginal	Failure
		(A+, A, A-)	(B+, B)	(B-, C+, C)	(F)
1. Laboratories and	Ability to understand and	High	Significant	Moderate to basic	Not reaching marginal
Term Paper	explain the relevant materials,				levels
	apply textbook knowledge in				
	engineering problems				
2. Final	Ability to understand	High	Significant	Moderate to basic	Not reaching marginal
Examination	and explain the				levels
	relevant materials				

Applicable to students admitted before Semester A 2022/23

Assessment Task	Criterion	Excellent	Good	Fair	Marginal	Failure
		(A+, A, A-)	(B+, B, B-)	(C+, C, C-)	(D)	(F)
1. Laboratories and Term Paper	Ability to understand and explain the relevant materials, apply textbook knowledge in engineering problems	High	Significant	Moderate	basic	Not reaching marginal levels
2. Final Examination	Ability to understand and explain the relevant materials	High	Significant	Moderate	basic	Not reaching marginal levels

Part III Other Information

1. Keyword Syllabus

- Materials characterization
- Overview of analytical techniques
- Microscopy
- Spectroscopy
- Optical microscopy
- Electron microscopy: scanning and transmission
- Scanning probe microscopy
- Electron probe microanalysis
- X-ray diffraction
- Ion beam techniques
- Secondary ion mass spectrometry
- Rutherford backscattering spectrometry
- Hall effect
- Capacitance-voltage measurement
- Seebeck effect
- Spectrophotometry
- Spectroscopic ellipsometry
- Modulated spectroscopy
- Photoluminescence
- X-ray photoelectron spectroscopy

2. Reading List

2.1 Compulsory Readings

1.	Encyclopedia of Materials Characterization, edited by C Richard Brundle, Charles A Evans, Jr
	and Shaun Wilson, Butterworth-Heinemann (1992)

2.2 Additional Readings

1.	X-ray Microanalysis in the Electron Microscope (4 th Edition), by J A Chandler, North Holland
	(1987)
2.	Methods of Surface Analysis: Techniques and Applications, edited J M E Walls, Cambridge
	University Press (1990)
3.	Analysis of Microelectronic Materials and Devices, edited by M. Grasserbauer and H W Werner,
	John Wiley & Sons (1991)
4.	Dopants and Defects in Semiconductors, Matthew D. McCluskey and Eugene E. Haller, Taylor
	& Francis Group (2012).
5.	Principles and Applications of Ion Beam Techniques for the Analysis of Solids and Thin Films,
	W. K. Chu, J. W> Mayer, M-A. Nicolet, T. M. Buck, G. Amsel, and F. Eisen, Thin Solid Films
	17, 1-41 (1973).
6.	Secondary Ion Mass Spectrometry, by Benninghoven, Rudenauer, and Werner, John Wiley &
	Sons (1987)
7.	Atomic and Nuclear Analytical Methods: XRF, Myssbauer, XPS, NAA and Ion-Beam
	Spectroscopic Techniques, Hem Raj Verma, Springer (2007).